

PHOENIX[®]

MODULAR CLEAN ROOM
COMPATIBLE SPUTTERING PLATFORM

THE PHOENIX IS A TURNKEY MULTI-CATHODE DC/RF
MAGNETRON SPUTTERING SYSTEM CAPABLE OF HANDLING
HIGH THROUGHPUT PRODUCTION REQUIREMENTS.

✓ R & D

BATCH PRODUCTION

✓ IN-LINE PRODUCTION

EVAPORATION

✓ SPUTTERING

✓ PECVD

MADE IN THE U.S.A. SINCE 1964

PHOENIX

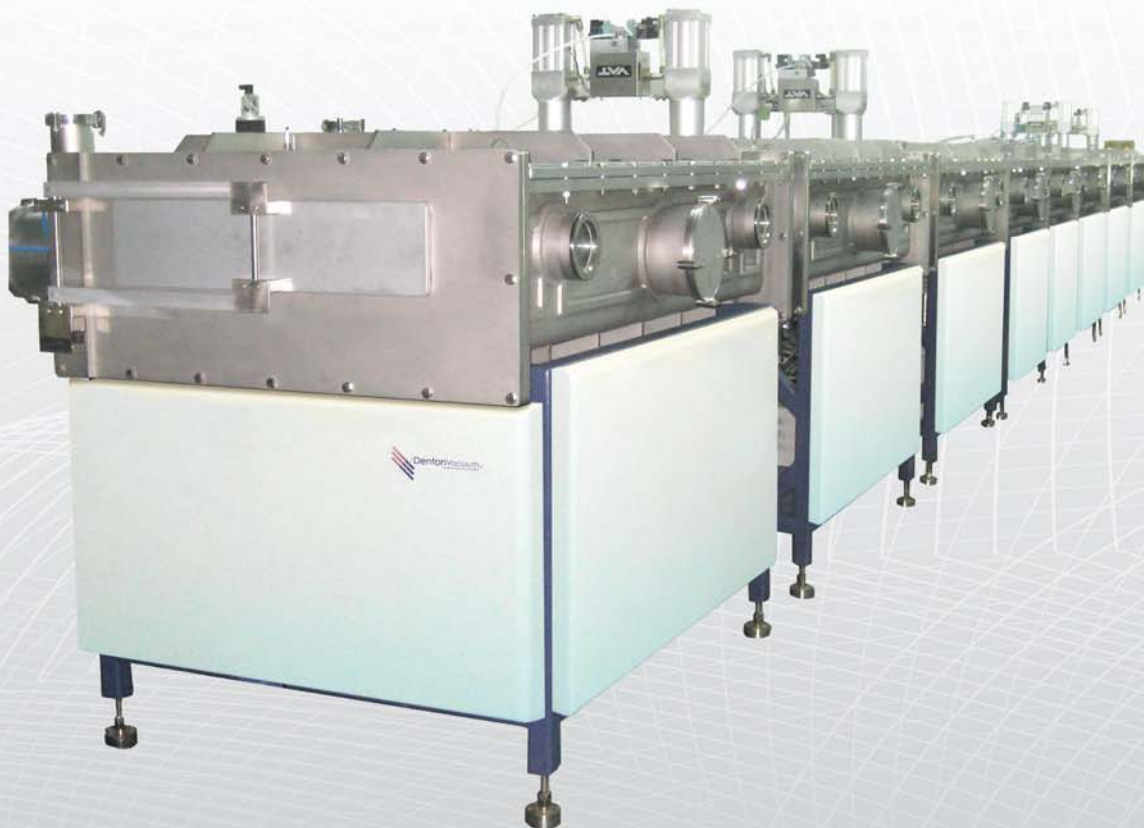
THE DENTON DIFFERENCE YOUR PROCESS IS OUR PROCESS

We collaborate with you to design a system that solves your exact thin film coating process needs. When we ship you a tool, it's production ready.

- Our systems scale to meet your production requirements
- We believe in customers for life
- Worldwide support network

AT DENTON WE CARE ABOUT YOUR SUCCESS

- FACTORY ACCEPTANCE TESTS
- PERSONALIZED TRAINING
- REMOTE, REAL-TIME SUPPORT
- CE/UL/CSA COMPLIANT SYSTEMS



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www.dentonvacuum.com

PHOENIX

CATHODES UP TO 60" LONG.

MULTI-CHAMBER, MULTI-PROCESS DESIGN

AVAILABLE IN VERTICAL OR HORIZONTAL CONFIGURATIONS TO BEST UTILIZE YOUR PRODUCTION REQUIREMENTS, FLOOR SPACE, AND WORKFLOW.

SCALABLE

THE MODULAR DESIGN ALLOWS YOU TO EASILY INCREASE PRODUCTION CAPABILITIES OR ADD DEPOSITION TECHNOLOGIES AS YOUR REQUIREMENTS CHANGE.

POWERFUL CONTROL SYSTEM

AVAILABLE IN SEMI-MANUAL MODE OR IN FULLY AUTOMATIC MODE WITH ONE PUSH AUTOMATION TO REDUCE SYSTEM DOWNTIME.

PROCESSPRO UPGRADE OFFERS:

1. **CONSISTENT CONTROLS** ACROSS ALL DENTON VACUUM PRODUCTS.
2. **STANDARD SOFTWARE** MAKES IT EASY TO SUPPORT AND AVOID COSTLY CUSTOMIZATION FEES.
3. **SOURCE CODE** FOR YOUR PROGRAMS SO YOU CAN CUSTOMIZE YOUR PROGRAMS.
4. **NETWORK CAPABILITIES** MAKES THE PHOENIX A NODE ON YOUR NETWORK ENABLING REAL-TIME, REMOTE SUPPORT AND UPGRADES.



MULTIPLE PUMPING CONFIGURATIONS

A VARIETY OF DIFFUSION, CRYOGENIC, AND TURBO PUMP CONFIGURATIONS ARE AVAILABLE TO FIT YOUR BUDGET AND PROCESS. REAR OR BOTTOM FITTED PUMPS PROVIDE EASY ACCESS FOR SERVICE BASED ON YOUR WORKSPACE NEEDS.

TYPICAL APPLICATIONS

PECVD

- Materials Research
- Small Batch Systems
- 3D Objects
- Coat a Variety of Materials

SPUTTERING

- Process Development
- Hard Coatings
- Semiconductor & MEMs
 - Interlayer Dielectric
 - Passivation Layers
- Production
- Nanotechnology
- Medical Devices
- OLEDs
- Protective Coatings

PHOENIX

OPTIONS

CLOSED LOOP CARRIER RETURN SYSTEM	SPUTTERING	PECVD
IN-SITU OPTICAL TRANSMISSION MONITORING	X	X
PLASMA EMISSION MONITORING FOR REACTIVE PROCESSES	X	X
AUTOMATED LOADING AND UNLOADING	X	X
EXTERNAL BUFFERING CASSETTES	X	X
LINEAR ION SOURCE FOR SUBSTRATE CLEANING	X	X

PUMP OPTIONS		
DIFFUSION	X	X
CRYOGENIC	X	X
TURBO	X	X
OIL FREE	X	X
DRY-SCROLL	X	X

specifications subject to change without notice



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